



EV085415213

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. .... 09/536,037  
Filing Date .... March 27, 2000  
Inventor .... Weimin (Michael) Li et al.  
Assignee .... Micron Technology, Inc.  
Group Art Unit .... 2822  
Examiner .... Toniae M. Thomas  
Attorney's Docket No. .... MI22-1398  
Title: Low k Interlevel Dielectric Layer Fabrication Methods

**SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT**

References - - See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

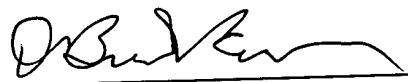
This Supplemental Information Disclosure Statement is being filed after the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925. Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

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Citation of these references is respectfully requested.

Respectfully submitted,

Date: 7-16-03

  
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D. Brent Kenady  
Reg. No. 40,045

<p style="text-align: right;">FMT-PTO-149</p> <p style="text-align: right;">O P E R A T I O N S</p> <p style="text-align: right;">JUL 16 2003</p> <p style="text-align: right;">U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE</p> <p style="text-align: right;">LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)</p>				ATTY. DOCKET NO. MI22-1398		SERIAL NO. 09/536,037	
				APPLICANT Weimin (Michael) Li et al.			
				FILING DATE March 27, 2000		GROUP 2822	
U.S. PATENT DOCUMENTS							
*Examiner Initial	Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
AA	6,001,747	12/14/1999	ANNA PRAGADA	438	790		
AB							
AC							
AD							
AE							
AF							
AG							
AH							
AI							
AJ							
AK							
AL							
FOREIGN PATENT DOCUMENTS							
	Document Number	Date	Country	Class	Subclass	Translation	
AM						Yes	No
AN							
AO							
AP							
AQ							
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
AR		"Silicon Processing for The VLSI Era"; Wolf, Stanley, Ph.D., Lattice Press 1986					
AS							
AT							
EXAMINER			DATE CONSIDERED				
<p>*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.</p>							